Fig. 1

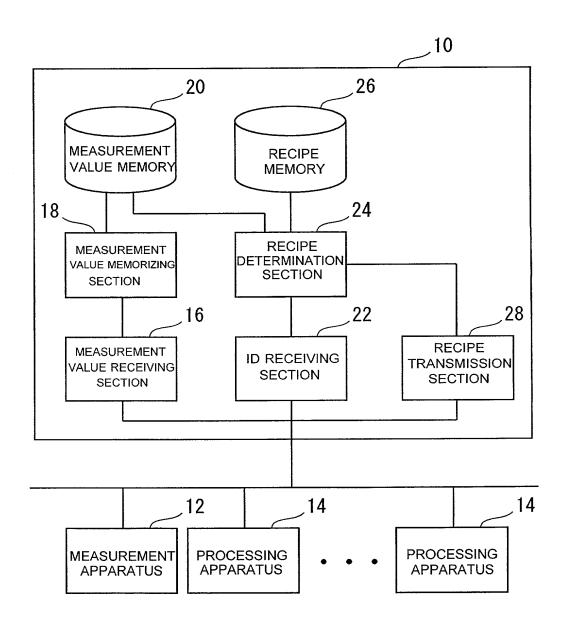
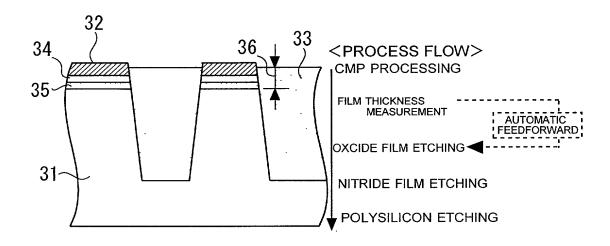
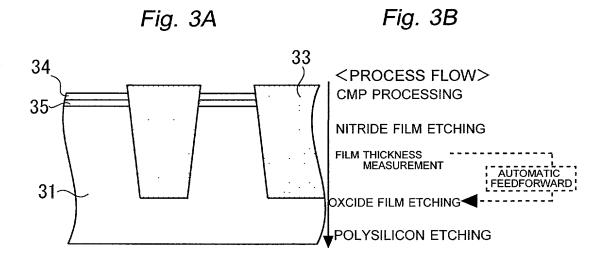


Fig. 2A

Fig. 2B





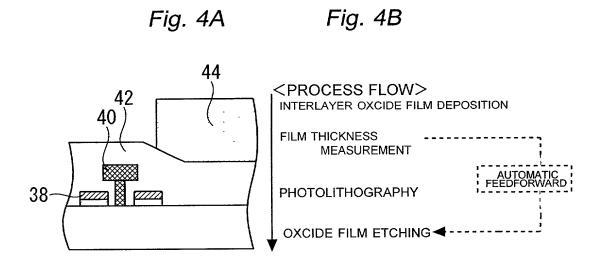


Fig. 5A

Fig. 5B

PROCESS FLOW>
INTERLAYER OXCIDE FILM DEPOSITION
IMPURITY CONCENTRATION
MEASUREMENT

PHOTOLITHOGRAPHY

OXCIDE FILM ETCHING

1. 5 1. 4 (SEFATIVE RATION (Mol%))

Fig. 6

AUTOMATIC FEEDFORWARD

Fig. 7A

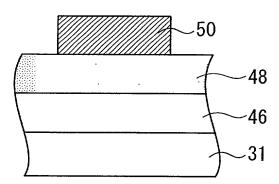


Fig. 7B

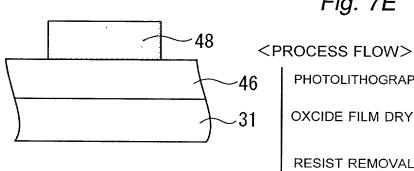
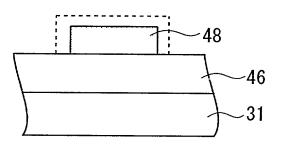


Fig. 7C





PHOTOLITHOGRAPHY

OXCIDE FILM DRY ETCHING

**RESIST REMOVAL** 

**DIMENTION MEASUREMENT** 

OXCIDE FILM WET ETCHING

DRY ETCHING

Fig. 7D

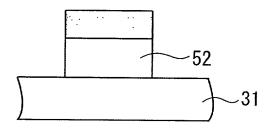


Fig. 8

